4　説明会の開催　本公表に基づく導入説明会を開催する。
⑴　開催日時　令和８年11月20日15時00分
⑵　開催場所　オンライン開催とする。（詳細は、導入説明書による。）
5　その他　この導入計画の詳細は導入説明書による。なお、本公表内容は予定であり、変更することがあり得る。
6　Summary
⑴　Classification of the products to be procured : 24
⑵　Nature and quantity of the products to be purchased : Autonomous Ultrahigh Vacuum Sputtering Growth System 1 Set
⑶　Type of the procurement : Purchase
⑷　Basic requirements of the procurement :
A　Ultrahigh vacuum sputtering system with revolving 10 targets 1 unit
a　Main vacuum system : A combination of a water-cooled turbo molecular and rotary pumps is used.
b　Base pressure : A vacuum is better than 1×10^{-7}Pa.
c　Targets : 10 targets can be replaced on a revolving holder without breaking a vacuum.
d　Sputtering cathode : DC, RF and both operation is possible. The sputtering incident is perpendicular to the plane. The number of cathodes is one, of which targets can be exchanged without breaking a vacuum in 1 min.
e　Linear shutter : To grow a wedged film, a linear shutter is installed without conflicting with the substrate shutter.
f　Manipulator : A manipulator has the following functionality ; in-plane rotation, vertical motion, substrate heating and substrate cooling.
B　Ultrahigh vacuum chamber for scanning tunnelling microscopy 1 unit
a　Main vacuum system : A combination of a water-cooled turbo molecular and rotary pumps is used.
b　Base pressure : A vacuum is better than 1×10^{-7}Pa.
c　STM : STM is installed to the chamber by bolts with necessary anti-vibration.
C　Ultrahigh vacuum chamber for co-sputtering 1 unit
a　Main vacuum system : A combination of a water-cooled turbo molecular and rotary pumps is used.
b　Base pressure : A vacuum is better than 1×10^{-5}Pa which is measured by a wide-range vacuum gauge.
c　Sputtering cathode : DC, RF and both operation is possible. At least four of the cathodes are installed for co-sputtering at the same time.
D　Transfer chamber 1 unit
a　The central chamber that performs vacuum transport of sample holders between rooms using a robot.
b　The chamber needs to hold over 4 connecting ports to chambers including the abovementioned ones.
c　Vacuum system : A combination of a water-cooled turbo molecular with magnetic levitation and rotary pumps is used.
d　Base pressure : A vacuum is better than 1×10^{-6}Pa.
e　Autonomous transfer system has elevation, rotation and extension functions. By teaching, autonomous transfer and manipulation can be achieved among the connected chambers.
E　Load-lock chamber 1 unit
a　Main vacuum system : A combination of a water-cooled turbo molecular and rotary pumps is used.
b　Base pressure : A vacuum is better than 1×10^{-4}Pa.
c　Sample stocker : At least five sample holder for a ϕ2 inch wafer can be stored and autonomously loaded for deposition and characterisation.
F　Controlling computer and programmable logic controller 1 unit
a　Components : One programmable logic controller for vacuum control with necessary functions and interlock, and one computer for general operation.
b　The following control needs to be achieved using the computer : Autonomous transfer of a substrate holder among chambers, vacuum, deposition, substrate heating and cooling in the abovementioned chambers.
⑸　Time limit for the submission of the requested material : 17 : 00　14 December, 2026
⑹　Contact point for the notice : Hiroaki Kawamura, Procurement Services Office, Finance Department, Tohoku University, 2―1―1 Katahira Aoba-ku Sendai-shi 980―8577 Japan TEL 022―217―4869

意見招請に関する公示

次のとおり調達物品の仕様書案の作成が完了したので、仕様書案に対する意見を招請します。
令和８年11月11日
文部科学省大臣官房会計課長　奥　篤史
◎調達機関番号　016　◎所在地番号　13
○第８号
1　調達内容
⑴　品目分類番号　71、27
⑵　購入等物品及び数量
文部科学省行政情報システムに係るネットワーク機器の更改　一式
2　意見の提出方法
⑴　意見の提出期限　令和８年12月２日17時00分（郵送の場合は必着のこと。）
⑵　提出先　〒100―8959 東京都千代田区霞が関３－２－２　文部科学省大臣官房会計課用度班契約第二係　篠　未来　電話03―5253―4111　内線2230
3　仕様書案の交付
⑴　交付期間　令和８年11月11日から令和８年12月２日まで。
⑵　交付場所　上記２⑵に同じ。
4　仕様書案の説明会
⑴　開催日時　令和８年11月16日14時00分
⑵　開催場所　文部科学省入札室
5　Summary
⑴　Classification of the services to be procured : 71, 27
⑵　Nature and quantity of the services to be required : Replacement of Network Equipment for the Ministry of Education, Culture, Sports, Science and Technology's Administrative Information System 1 Set
⑶　Time limit for the submission of comments : 17 : 00　2 December, 2026
⑷　Contact point for the notice : SHINO Mirai, Supplies Section, Budget and Accounts Division, Minister's Secretariat, Ministry of Education, Culture, Sports, Science and Technology, 3―2―2 Kasumigaseki Chiyoda-ku Tokyo 100―8959 Japan, TEL 03―5253―4111 ex. 2230

意見招請に関する公示

次のとおり調達特定役務の仕様書案の作成が完了したので、仕様書案に対する意見を招請します。
令和８年11月11日
特許庁総務部会計課長　細谷　賢二
◎調達機関番号　019　◎所在地番号　13
1　調達内容
⑴　品目分類番号　71、27
⑵　購入等特定役務及び数量　特許庁内製システム開発支援サービス　一式
2　意見の提出方法
⑴　意見の提出期限　令和８年12月１日17時00分（郵送の場合は必着のこと。）
⑵　提出先　〒100―8915 東京都千代田区霞が関三丁目４番３号　特許庁総務部会計課契約第二班契約第四係　河原　研治　電話03―3581―1101　内線2214
3　仕様書案の交付
⑴　交付期間　令和８年11月11日から令和８年12月１日まで
⑵　交付場所　特許庁ホームページによる
https://www.jpo.go.jp/news/chotatsu/iken/index.html